

Applicant(s): Steve Biellak, et al.
Title: System and Methods for a Wafer Inspection System Using Multiple Angles and Multiple Wavelength Illumination
Application No.: 09/891,693 Filing Date: June 26, 2001
Examiner: Hoa Q. Pham Group Art Unit: 2877
Docket No.: TNCR.179US0 Conf. No.: 1752

Mail Stop RCE
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Transmitted herewith are the following documents in the above-identified application:

- (1) Return Receipt Postcard;
- (2) Transmittal Letter (1 page - in duplicate);
- (3) Request for Continued Examination (RCE)(1 page);
- (4) Amendment (28 pages);
- (5) Amendment Attachment - Article entitled: "Silicon-On-Insulator Technology"
- (6) Petition For Extension of Time;
- (7) Terminal Disclaimer (2 pages);
- (8) Supplemental Information Disclosure Statement (2 pages);
- (9) PTO Form 1449 (1 sheet)
- (10) 7 Cited References

The fee has been calculated as shown below:

<input checked="" type="checkbox"/>	Fee for Terminal Disclaimer	\$	130.00
<input checked="" type="checkbox"/>	Fee for Extension of Time		120.00
<input checked="" type="checkbox"/>	Fee for RCE		790.00
		Total:	\$ 1040.00


- ☒ Conditional Petition for Extension of Time: If an extension of time is required for timely filing of the enclosed document(s) after all papers filed with this transmittal have been considered, an extension of time is hereby requested.
- ☒ Please charge all required fees required to our Deposit Account No. 502664.

EXPRESS MAIL NO.:

EV321704785US

February 22, 2005

Respectfully submitted,


Gerald P. Parsons Date
Reg. No. 24,486